

REMARKS

A request for continued examination is being filed concurrently herewith in this patent application.

Claims 26 through 36 remain pending in the present application. Claims 26 and 36 are the independent claims.

Claims 26 and 27 have been amended herein. No new matter has been added.

Claims 26-36 were previously allowed in this application. The amendment to independent Claim 26 merely changes the phrase "when a reduction" to "after a reduction." The amendment to Claim 27 merely changes the phrase "the anodization terminates when" to "the anodization terminates after." Therefore, the present application should be in condition for allowance.

Applicants submit that this application is in condition for allowance. Favorable consideration of the claims and an early passage to issue of the present application are requested.

Favorable consideration and early examination on the merits are requested.

Applicants' undersigned attorney may be reached in our Washington, D.C. office by telephone at (202) 530-1010. All correspondence should continue to be directed to our below listed address.

Respectfully submitted,



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APPENDIX

VERSION SHOWING CHANGES MADE TO CLAIMS

26. (Amended) A method of producing a nanostructure comprising an anodized film including a nanohole on a substrate having a surface containing at least one material selected from the group consisting of semiconductors, noble metals, Mn, Fe, Co, Ni, Cu and carbon, said nanoholes passing through said anodized film from the surface of said anodized film to the surface of said substrate, wherein said method comprising the steps of:

(i) forming a film containing aluminum on the substrate having a surface containing at least one material selected from the group consisting of semiconductors, noble metals, Mn, Fe, Co, Ni, Cu and carbon; and

(ii) anodizing said film containing aluminum,
wherein in step (ii) the anodization is conducted while monitoring an anodization current and the anodization of said film containing aluminum terminates after [when] a reduction in said anodization current from a steady-state value is detected.

27. (Amended) A method of producing a nanostructure according to Claim 26, wherein the anodization terminates after [when] the anodization current is decreased from the steady-state value of 95% or below of the steady-state value.

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